

**17.** The method, as defined in claim **15**, further including the step of creating a funnel-shaped channel entrance for the plurality of nanopores.

**18.** The method, as defined in claim **15**, wherein the emissive oxide composition is adjusted by mixing selected oxides to adjust electrical resistance.

**19.** The method, as defined in claim **15**, further including the step of adding additional patterned layers on the Al layer.

**20.** The method as defined in claim **15** further including the step after depositing the Al layer of applying photolithography to develop at least one pattern; followed by developing microchannels through the steps of at least one of etching and photoresist and removing the Al layer.

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